

Abstract

The present invention relates to a device (10) for drying and/or cleaning pot-shaped hollow bodies (12), in particular transport containers for semiconductor wafers or for EUV lithography masks, wherein the device (10) has a cleaning device (44) that can be or is introduced into the inner hollow body space (12) through the hollow body opening (24) and that has a first dispensing unit (46) by which a first fluid for cleaning and/or drying the inner hollow body surface (18) can be dispensed and has a second dispensing unit (48) by which a second fluid for cleaning and/or drying the inner hollow body surface (18) can be dispensed, and an adjustment device (50) by which the first dispensing unit (46) and the second dispensing unit (48) are movable independently of one another. The invention additionally relates to a method of drying and/or cleaning pot-shaped hollow bodies (12) using such a device (10).

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(Figure 1)